ABSTRACT

A substrate transfer apparatus and a substrate processing apparatus are disclosed. The substrate transfer apparatus comprises: a support column (110); a robot (120), configured to support a substrate (40); a lifting mechanism (130), including a lifting drive device (134) and lifting support members, wherein the lifting drive device is configured to drive the lifting support members to perform ascending and descending movements; a rotating mechanism (140), including a support base (141), wherein the rotating mechanism is rotatably connected to the support column via the support base, and the rotating mechanism is configured to drive the robot and a first support member (131) to rotate around the support column; and a plurality of guide shafts (150) , distributed around the axis of the support column, wherein one end of each guide shaft is connected to the support base, and the other end of each guide shaft is connected to the first support member, such that the rotation of the support base drives the first support member and the robot to rotate. The substrate transfer apparatus and the substrate processing apparatus can reduce the fitting tolerance requirements for perpendicularity and concentricity between the plurality of guide shafts and the support base, thereby lowering the machining cost of the support base. In addition, the tilting phenomenon of the robot can be ameliorated.